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CERTIFICATE OF TRANSMISSION

March 11, 2003

Atty Docket No. : MART4591
Appl. No. : 09/759,899
Filing Date : January, 12, 2001
Pages : Cover + 6

BY FACSIMILE ONLY

Fax No. : 703-872-9310
Attention : Examiner AHMED, SHAMIM
Group Unit : 1765
From : Jiawei Huang, Reg. No. 43,330
MESSAGE : Enclosed is an Amendment in 6 pages.

Sir:

I hereby certify that this correspondence is being facsimile transmitted to the Patent and Trademark Office on March 11, 2003 at the above indicated fax number.

Sign by Michelle Chang
Michelle Chang

Note: This facsimile transmission is intended only for the use of the individual or entity to which it is addressed, and may contain information that is privileged, confidential and exempt from disclosure under applicable law. If the reader is not the intended recipient, or the employee or agent responsible for delivering the message to the intended recipient, you are hereby notified that any dissemination, distribution or copying of this communication is strictly prohibited. If you have received this transmission in error, please kindly notify us immediately, and return the original message to us at the above address. We greatly appreciate your cooperation.

Atty Docket No.: MART4591

Serial No.: 09/759,899

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of :

Application No. : 09/759,899
Filed : January 12, 2001
For : TREATMENT ON SILICON OXYGNITRIDE
Applicant : I. T. Chen
Examiner : Ahmed, Shamim
Art Unit : 1765

No fee is believed to be due. However, the Commissioner is authorized to charge any fees required in connection with the filing of this paper to account No. 50-0710 (Order No. MART4591).

AMENDMENT AND RESPONSE TO OFFICE ACTION**BOX Non-Fee Amendment**

Assistant Commissioner of Patents and Trademarks
Washington, DC 20231

Dear Sir:

The Office Action mailed on December 12, 2002 has been carefully considered. In response thereto, please enter the following amendments and consider the following remarks.

In The Title:

Please substitute the following clean copy title for the pending title:

--METHOD TO REMOVE SILICON OXIDE MATERIAL GENERATED DURING
REMOVAL OF PHOTORESIST--